

**PATENT**

Attorney Docket No. 007996 USA CO1/IMPLANT/CONDUCTIVE/JB1 [as amended]

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): Donald W. Berrian  
Application No.: 10/694,162  
Filed: 27 October 2003  
Examiner: Vanore, David A.  
Group Art Unit: 2881  
Confirmation No.: 3050

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Invention Title: SYSTEM AND METHOD FOR IMPLANTING A WAFER  
WITH AN ION BEAM

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**REQUEST TO AMEND ATTORNEY DOCKET NUMBER**

Applicants hereby request the following amendment to the Attorney Docket  
Number in the above-identified patent application:

Please delete "413283" and substitute  
"007996USACO1/IMPLANT/CONDUCTIVE/JB1" therefor.

Date: 17 Jun 2004

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**CERTIFICATE OF TRANSMITTAL UNDER 37 C.F.R. 1.8**

I hereby certify that, on the date shown below, this correspondence is being transmitted to facsimile number 703-872-9306 via facsimile to: TC 281, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

June 17, 2004  
Date

Janice Price  
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